IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Atsushi NISHIZAWA

Serial No

09/751,979

Filed

January 23, 2001

Title

MANUFACTURING METHOD OF SEMICONDUCTOR...

Group Art Unit

1765

May 4, 2001

Attn: Customer Corrections Division Assistant Commissioner for Patents

Washington, D.C. 20231

OCT 1 9 2007
TC 1700

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REQUEST FOR CORRECTED FILING RECEIPT

SIR:

We received the filing receipt on the above-referenced case, copy enclosed,

wherein the ASSIGNMENT FOR PUBLISHED PATENT APPLICATION was incorrectly listed as: NEC CORP.

Please change the same to read: NEC CORPORATION. Also the TITLE was incorrectly listed as:

MANUFACTURING METHOD SEMICONDUCTOR INTERGRATED CIRCUIT INCLUDING

SIMULTANEOUS FORMATION OF VIA HOLE REACHING METAL WIRING AND CONCAVE GROOVE

IN INTERLAYTER.... Please change the same to read: MANUFACTURING METHOD OF

SEMICONDUCTOR INTERGRATED CIRCUIT INCLUDING SIMULTANEOUS FORMATION OF VIA

HOLE REACHING METAL WIRING AND CONCAVE GROOVE IN INTERLAYER FILM AND

SEMICONDUCTOR INTERGRATED CIRCUIT MANUFACTURED WITH THE MANUFACTURING

METHOD.

Any fee, due as a result of this paper not fully covered by an enclosed check, may

be charged on Deposit Account No. 08-1634.

Respectfully/submitted

Samson Helfgott Reg. No. 23,072

Helfgott & Karas, P.C. 60th Floor **Empire State Building** New York, New York 10118 Tel. (212) 643-5000

Docket No.:18.159 SH:eju:FILREC

> Any fee due with this paper, not fully served by an enclosed check, may be charged on deposit Acct. No. 08-1634

I HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE AS FIRST CLASS-MAIL IN AN ENVELOPE ADDRESSED TO: COMMISSIONER OF PATENTS AND TRADEMARKS, WASHINGTON, D.C. 20231, ON THE DATE INDICATED BELOW.

DATE



APR 02 2001

UNITED STATES PATENT AND TRADEMARK OFFICE

COMMISSIONER FOR PATENTS
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WASHINGTON, D.C. 2023I
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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY.DOCKET.NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/751,979	12/29/2000	1765	710	NECW 18 159	6	12	2

CONFIRMATION NO. 9046

HELFGOTT & KARAS, P.C. 60th Floor Empire State Building New York, NY 10118-0110

OCT 1 9 2001

RE.

OC00000005913685

TC 1700

Date Mailed: 03/28/2001

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the PTO processes the reply to the Notice, the PTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Atsushi Nishizawa, Tokyo, JAPAN;

Assignment For Published Patent Application

NEC-CORPORATION

Continuing Data as Claimed by Applicant

Foreign Applications

JAPAN 2000-009221 01/18/2000

If Required, Foreign Filing License Granted 03/27/2001

Projected Publication Date: 07/19/2001

Non-Publication Request: No

Early Publication Request: No

Title

oF

Manufacturing method semiconductor integrated circuit including simultaneous formation of via hole reaching metal wiring and concave groove in interlayter film and semiconductor integrated circuit manufactured with the manufacturing method

Preliminary Class

438

INTERLAYER

Data entry by: IBRAHIM, SADIE

Team: OIPE

Date: 03/28/2001